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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
KEVIN R. LENSING

Serial No.: 09/897,205

Filed: July 2, 2001

For: **METHOD OF USING SCATTEROMETRY
MEASUREMENTS TO CONTROL
PHOTORESIST ETCH PROCESS**

Examiner: Kumiko C. Koyama

Group Art Unit: 2876

Att'y Docket: 2000.071900/TT4369

Customer No.: 23720

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RESPONSE TO FINAL OFFICE ACTION DATED JULY 14, 2003

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

**CERTIFICATE OF MAILING
37 C.F.R. 1.8**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below:

September 15, 2003

Date

Mary Paul
Signature

This paper is submitted in response to the Final Office Action dated July 14, 2003, for which the three-month date for response is October 14, 2003.

A fee in the amount of \$110.00 is believed to be due in connection with the Terminal Disclaimer filed herewith. **The Assistant Commissioner is authorized to deduct such fee, and any other fees required under 37 C.F.R. §§ 1.16 to 1.21, from Advanced Micro Devices, Inc. Deposit Account No. 01-0365/TT4369.** In the event the monies in that account are insufficient, the Assistant Commissioner is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.071900.

09/18/2003 RWO:DAF1-00000114-010365- 09897205-

01-FC:1814

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